

GENERAL PURPOSE SPINNER OPERATING PROCEDURES

10/19/2005

NOTE: Do not alter any recipes.

Precheck

1. Select the correct size wafer chuck. Available are: 4-inch, 3-inch and piece.
2. Push black release button on spinner lid and **gently** lift lid to open position.
Do not force or handle the plastic safety shield.
3. Align the flat of the chuck washer to the flat of the spindle.
4. Push the wafer chuck securely on the spindle shaft.
5. Position test wafer in the center of the chuck. This test is to verify the programmed recipe steps. If the recipe has been altered, please contact staff to reprogram the recipe.
6. Gently lower the spinner lid. ***Do not force or handle the plastic safety shield.***
7. On controller press **RECIPE** + [number of desired recipe]
8. To begin recipe steps, press **START** button located on wet bench deck.

RECIPE	STEP 1	STEP 2	STEP 3	STEP 4	STEP 5	STEP 6
0 -- Clean						
1 -- Spray Developing	0 RPM 3 sec	1500 RPM 10K Ramp 30 sec	0 RPM 500 Ramp 0 sec			
2 -- 2500	500 RPM 500 Ramp 5 sec	2500 RPM 3000 Ramp 30 sec	0 RPM 500 Ramp 0 sec			
3 -- 2500	2500 RPM 250 Ramp 10 sec	2500 RPM 20 sec	0 RPM 250 Ramp 10 sec			
4 -- 500/3000	100 RPM 100 Ramp 5 sec	500 RPM 500 Ramp 7 sec	3000 RPM 3000 Ramp 30 sec	0 RPM 500 Ramp 0 sec		
5 -- 5500	0 RPM 3 sec	5500 RPM 10K Ramp 30 sec	0 RPM 500 Ramp 0 sec			
6 -- 4000	0 RPM 3 sec	4000 RPM 10K Ramp 30 sec	0 RPM 500 Ramp 0 sec			
7 -- 2000	0 RPM 3 sec	2000 RPM 10K Ramp 60 sec	0 RPM 500 Ramp 0 sec			
8 -- 6000	0 RPM 3 sec	3000 RPM 10K Ramp 30 sec	0 RPM 500 Ramp 0 sec			
9 -- 500/1000/6000	0 RPM 6 sec	500 RPM 1000 Ramp 10 sec	800 RPM 100 Ramp 60 sec	6000 RPM 2500 Ramp 10 sec	0 RPM 500 Ramp 0 sec	

9. After test run, push black release button on spinner lid and **gently** lift lid to open position.
Do not force or handle the plastic safety shield.
10. Remove test wafer and position the next wafer in the center of the chuck.
11. Gently lower the spinner lid. **Do not force or handle the plastic safety shield.**
12. Repeat recipe process until complete.

End

1. Push black release button on spinner lid and **gently** lift lid to open position. **Do not force or handle the plastic safety shield.**
2. Remove wafer.
3. To clean bowl, place test wafer on chuck and close lid.
4. On controller press **RECIPE + 0** and **START** button located on wet bench deck.

RECIPE	PR	STEP 1 Spray acetone Spray IPA	STEP 2 Spin Dry	STEP 3 Stop
0 -- Clean	none	30 sec 1000rpm spin 1000/sec ramp	30 sec 3000rpm spin 1000/sec ramp	0 sec 0rpm spin 500/sec ramp

5. While chuck is spinning, spray acetone on test wafer. Follow with an isopropanol spray.
6. Allow spin drying.
7. Open lid and remove test wafer and chuck.
8. Store chuck in box located on bench deck. **Do not remove chucks from this bench.**
9. Wipe out liner and bowl with cleanroom wipes.
10. Log use.